

Title (en)

THIN FILM COATING SYSTEM AND METHOD

Title (de)

DÜNNFILMBESCHICHTUNGSSYSTEM UND VERFAHREN

Title (fr)

SYSTÈME ET PROCÉDÉ DE REVÊTEMENT DE FILM, MINCE

Publication

**EP 2220263 A1 20100825 (EN)**

Application

**EP 08841116 A 20081027**

Priority

- US 2008012170 W 20081027
- US 99606307 P 20071026

Abstract (en)

[origin: WO2009055065A1] A method and system for depositing a thin film on a substrate. In the system a target material is deposited and reacted on a substrate surface to form a substantially non- absorbing thin film. The volume of non-absorbing thin film formed per unit of time may be increased by increasing the area of the surface by a factor of "x" and increasing the rate of deposition of the target material by a factor greater than the inverse of the factor "x" to thereby increase the rate of formation of the volume of non-absorbing thin film per unit of time.

IPC 8 full level

**C23C 14/50** (2006.01); **C23C 14/34** (2006.01)

CPC (source: EP)

**C23C 14/3492** (2013.01); **C23C 14/505** (2013.01)

Designated contracting state (EPC)

AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MT NL NO PL PT RO SE SI SK TR

Designated extension state (EPC)

AL BA MK RS

DOCDB simple family (publication)

**WO 2009055065 A1 20090430**; CN 101809185 A 20100818; CN 101809185 B 20130508; EP 2220263 A1 20100825; EP 2220263 A4 20140604; JP 2011500971 A 201110106

DOCDB simple family (application)

**US 2008012170 W 20081027**; CN 200880106268 A 20081027; EP 08841116 A 20081027; JP 2010531062 A 20081027